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Seiko Instruments Inc.
8, Nakase 1-Chome, Mihama-ku,
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2. Name and address of receiving party(ies):

SII NanoTechnology Inc.
8, Nakase 1-Chome, Mihama-ku,
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Execution Date: February 14, 2005

4. Application number(s) or patent number(s):

If this document is being filed together with a new application, the execution date of the application is: n/a

A. Patent Application No.(s) n/a

B. Patent No.(s) 6,621,082

Additional numbers attached? ☒ Yes ☐ No

5. Name and address of party to whom correspondence concerning document should be mailed:

Lawrence J. McClure, Esq.
HOGAN & HARTSON L.L.P.
500 South Grand Avenue, Suite 1900
Los Angeles, CA 90071

6. Total number of applications and patents involved: [1]

7. Total fee (37 CFR 3.41) $3320.00 (83 applications x $40 each)

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Attachment of Additional Numbers

Patent Number	Issue Date	First Named Inventor	Title
4,902,530	February 20, 1990	Yasaka	Method of Correcting A Pattern Film
4,849,642	July 18, 1989	Katsumi	Method for Repairing A Pattern Film
4,851,097	July 25, 1989	Hattori	Apparatus for Repairing A Pattern Film
4,874,460	October 17, 1989	Nakagawa	Method and Apparatus for Modifying Patterned Film
4,983,830	January 8, 1991	Iwasaki	Focused Ion Beam Apparatus Having Charged Particle Energy Filter
4,967,601	November 6, 1990	Teramoto	Viscoelasticity Measuring Apparatus
5,309,171	May 3, 1994	Nakatani	Graph Display Device
5,013,159	May 7, 1991	Nakamura	Thermal Analysis Apparatus
5,060,247	October 22, 1991	Watanabe	Fluorescent X-Ray Film Thickness Gauge
4,979,896	December 25, 1990	Kinoshita	Cooling Device Of Heating Furnace In Thermal Analyzer
5,023,453	June 11, 1991	Adachi	Apparatus for Preparation and Observation of a Topographic Section
4,984,469	January 15, 1991	Take	Amplitude Measurement Device for Viscoelasticity Analysis
5,028,780	July 2, 1991	Kaito	Preparation and Observation Method of Micro-Section
5,117,639	June 2, 1992	Take	Automatic Cooling System
5,023,457	June 11, 1991	Yonezawa	Electron Beam Device
5,142,145	August 25, 1992	Yasutake	Composite Scanning Tunneling Microscope
5,117,110	May 26, 1992	Yasutake	Composite Scanning Tunnelling Microscope with a Positioning Function
5,153,440	October 6, 1992	Yasaka	Method of Stabilizing Operation for a Liquid Metal Ion Source
5,148,024	September 15, 1992	Watanabe	Ion Beam Processing Apparatus and Gas Gun Therefor
5,111,053	May 5, 1992	Suzuki	Controlling A Liquid Metal Ion Source By Analog Feedback And Digital CPU Control
5,215,923	June 1, 1993	Kinoshita	Method For Automatic Sample Positioning
5,154,085	October 13, 1992	Takeda	Tension Type Dynamic Viscoelasticity Measuring Apparatus
5,182,950	February 2, 1993	Takeda	Tension Type Dynamic Viscoelasticity Measuring Apparatus
5,287,749	February 22, 1994	Nakamura	Thermomechanical analyzer
5,293,404	March 8, 1994	Takeda	Thermal measuring and testing system having synchronized sample transporting means

Patent Number	Issue Date	First Named Inventor	Title
5,200,975	April 6, 1993	Kato	Furnace for viscoelasticity measuring device with concentric gas cooling shield
5,215,377	June 1, 1993	Sugano	Thermogravimetric apparatus
5,379,239	January 3, 1995	Nakatani	Waveform display device
5,405,734	April 11, 1995	Aita	Method for correcting a patterned film using an ion beam
5,228,778	July 20, 1993	Nakatani	Heat analyzer
5,299,252	March 29, 1994	Takahashi	Fluorescent X-ray film thickness measuring apparatus
5,324,935	June 28, 1994	Yasutake	Scanning probe microscope having a directional coupler and a Z-direction distance adjusting piezoelectric element
5,306,087	April 26, 1994	Nakamura	Apparatus for thermogravimetry
5,334,834	August 2, 1994	Ito	Inductively coupled plasma mass spectrometry device
5,376,883	December 27, 1994	Kaito	Analysis of integrated circuit operability using a focused ion beam
5,389,884	February 14, 1995	Nakamura	Parallel plate dielectric constant measuring apparatus having means for preventing sample deformation
5,574,280	November 12, 1996	Fujii I.	Focused ion beam apparatus and method
5,423,514	June 13, 1995	Wakiyama	Alignment assembly for aligning a spring element with a laser beam in a probe microscope
5,448,504	September 5, 1995	Nakatani	Apparatus for thermal analysis
5,418,351	May 23, 1995	Take	Automatic cooling apparatus
5,466,066	November 14, 1995	Hidaka	Thermogravimetric apparatus with a balance arm vibrating function
5,345,183	September 6, 1994	Take	Dielectric constant-measuring apparatus
6,061,425	May 9, 2000	Sato	Coating thickness gauge by X-ray fluorescence
5,484,252	January 16, 1996	Mutoh	Sample holding apparatus
5,477,049	December 19, 1995	Kitamura	Particle analysis method
5,426,299	June 20, 1995	Nakagawa	Inductive plasma mass spectrometer
5,477,048	December 19, 1995	Nakagawa	Inductively coupled plasma mass spectrometer
5,370,457	December 6, 1994	Iizuka	Thermomechanical analyzer
5,452,614	September 26, 1995	Kato	Dynamic viscoelasticity apparatus
5,444,245	August 22, 1995	Kitamura	Method of automatically setting coordinate conversion factor
5,440,121	August 8, 1995	Yasutake	Scanning probe microscope
5,440,122	August 8, 1995	Yasutake	Surface analyzing and processing apparatus
5,525,806	June 11, 1996	Iwasaki	Focused charged beam apparatus, and its processing and observation method

Patent Number	Issue Date	First Named Inventor	Title
5,442,949	August 22, 1995	Kinoshita	Thermal analyser
5,489,339	February 6, 1996	Hattori.	Microelectronic processing machine
5,506,400	April 9, 1996	Honma.	Scanning type probe microscope
5,425,066	June 13, 1995	Takahashi	Method of finding the center of a band-shaped region
5,457,725	October 10, 1995	Sata	Analyzing method for foreign matter states
5,438,197	August 1, 1995	Fujii	Focused ion beam apparatus
5,599,104	February 4, 1997	Nakamura	Thermal analysis instrument
5,483,065	January 9, 1996	Sato	Electron beam microanalyzer
6,395,347	May 28, 2002	Adachi	Micromachining method for workpiece observation
5,541,973	July 30, 1996	Tamura	Micro area analyzing method
5,711,604	January 27, 1998	Nakamura	Method for measuring the coefficient of heat conductivity of a sample
5,669,554	September 23, 1997	Nakamura	Humidity control thermal analyzer
5,650,614	July 22, 1997	Yasutake	Optical scanning system utilizing an atomic force microscope and an optical microscope
6,124,142	September 26, 2000	Fujino	Method for analyzing minute foreign substance elements
6,355,495	March 12, 2002	Fujino	Method and apparatus for analyzing minute foreign substance, and process for semiconductor elements or liquid crystal elements by use thereof
5,877,035	March 2, 1999	Fujino	Analyzing method and apparatus for minute foreign substances, and manufacturing methods for manufacturing semiconductor device and liquid crystal display device using the same
6,255,127	July 3, 2001	Fujino	Analyzing method and apparatus for minute foreign substances, and manufacturing methods for manufacturing semiconductor device and liquid crystal display device using the same
5,718,097	February 17, 1998	Kinoshita	Sample container sealer having function of setting load
5,826,983	October 27, 1998	Nakamura	Thermomechanical analyzer equipped with a thermogravimetry function
6,031,379	February 29, 2000	Takada	Plasma ion mass analyzing apparatus
5,982,172	November 9, 1999	Ishikawa	Method of detecting plastic deformation in steel using a differential type magnetic field sensor
5,804,821	September 8, 1998	Nakagawa	Plasma ion source mass analyzer
6,118,122	September 12, 2000	Koyama	Ion beam working apparatus
6,057,516	May 2, 2000	Nakamura	Thermogravimetric instrument
5,969,355	October 19, 1999	Fujii	Focused ion beam optical axis adjustment method and focused ion beam apparatus
5,917,186	June 29, 1999	Fujii	Focused ion beam optical axis adjustment method and focused ion beam apparatus
6,154,517	November 28, 2000	Takahashi	Fluorescent X-ray spectroscope

Patent Number	Issue Date	First Named Inventor	Title
6,365,905	April 2, 2002	Koyama	Focused ion beam processing apparatus
6,599,010	July 29, 2003	Suzuki	Thermo-mechanical analyzer

ASSIGNMENT OF PATENT RIGHTS FOR THE UNITED STATES

FOR VALUE RECEIVED, **Seiko Instruments Inc.** ("hereinafter called the "Assignor")

hereby sells, assigns, transfers and conveys unto **SII NanoTechnology Inc.**

a corporation of **Japan**

having a place of business at

8, Nakase 1-chome, Mihama-ku,
Chiba-shi, Chiba, Japan

its successors, assigns and legal representatives (hereinafter called the "Assignee"), its entire right, title and interest in and to the following United States Letters Patents, and in and to all divisions, continuations, reissues and extensions thereof:

Patent Number	Issue Date	First Named Inventor	Title
6,621,082	September 16, 2003	Morita	Automatic Focusing System for Scanning Electron Microscope Equipped with Laser Defect Detection Function
4,902,530	February 20, 1990	Yasaka	Method of Correcting A Pattern Film
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6,365,905	April 2, 2002	Koyama	Focused ion beam processing apparatus
6,599,010	July 29, 2003	Suzuki	Thermo-mechanical analyzer

AND Assignor authorizes and empowers the Assignee or its nominees to invoke and claim for any application for patent or other form of protection for said inventions, the benefit of the right of priority provided by the International Convention for the Protection of Industrial Property, as amended, or by any convention which may henceforth be substituted for it, and to invoke and claim such right of priority without further written or oral authorization from Assignor.

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Signature: Toshihiko Sakuhara Date: February 14, 2005

Printed Name: Toshihiko Sakuhara

Title: General Manager
of Seiko Instruments Inc.